



Patent  
Attorney's Docket No. 015290-502

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of	)	<b>MAIL STOP: NON-FEE</b>
	)	<b>AMENDMENT</b>
Helen H. ZHU et al.	)	
	)	Group Art Unit: 2823
Application No.: 09/820,694	)	
	)	Examiner: J. J. Maldonado
Filed: March 30, 2001	)	
	)	Confirmation No.: 7374
For: METHOD OF PLASMA ETCHING	)	
SILICON NITRIDE	)	

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated June 5, 2003, please amend the above-identified application as follows: